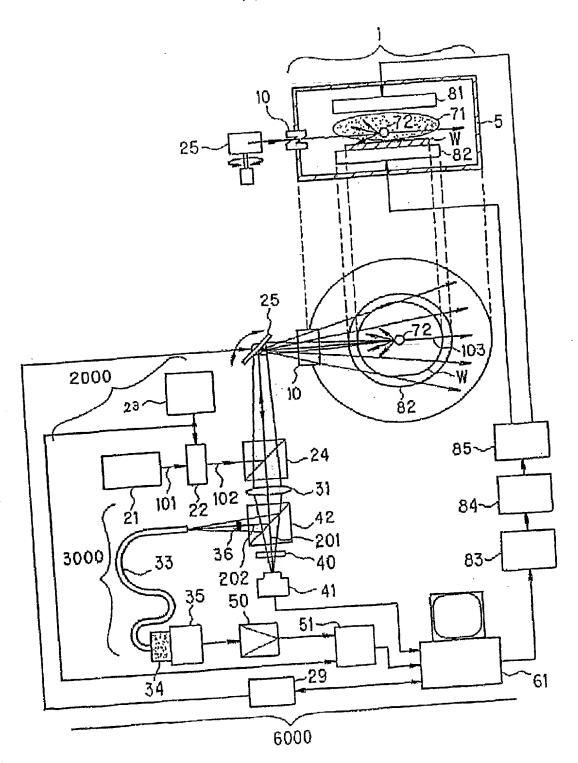
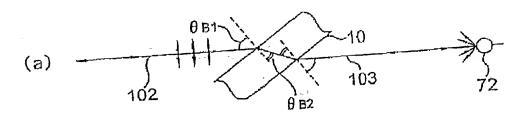
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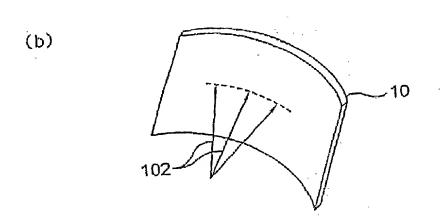
[図1]

図1



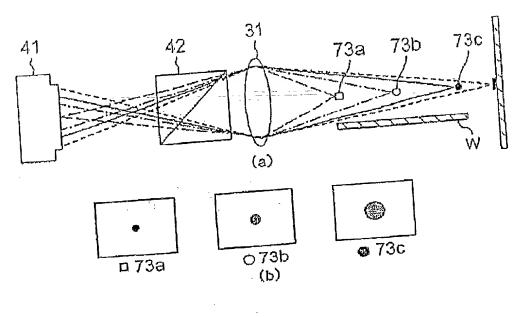
[図2]



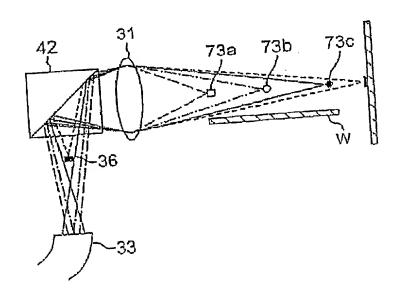


[図3]

図 3



[図4]



2000年 2月 8月 17時19分

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D99008581Al.el

[図5]

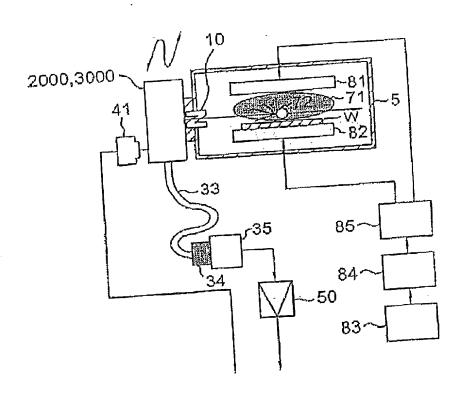
図5 5.5

laser scattering due to contaminants aminanis (with no modulation /s ynchronization detection) 異物による (with no medula レーザ散乱光 (変調・同期検波をしない場合) plasmaemission (Doumponent) laser scattering doe to 異物による光/ontaminants (with modulation) (変調・同期検波の場合) Synchronization Letection) プラズマ発光 (箇)水以分) -170kHZ 300 400 B00 80 532nm (レーザ液長) (aser wavelength servine mavelength ブラズマ発光 (RF=400kHz成分)

plasma emission (RF=400 HHz component)

ファイ<u>ル名 = D99008581A1.el</u>

【図6】



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No. 3764 P. 33

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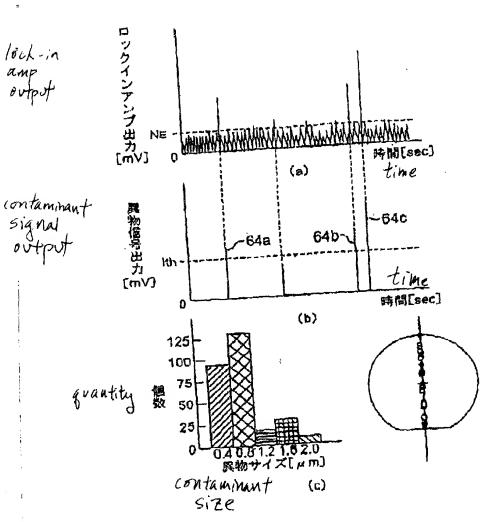
ページ(44/ 61)

= 039008581A1.el

[四7]

图7 Fig.7

signal



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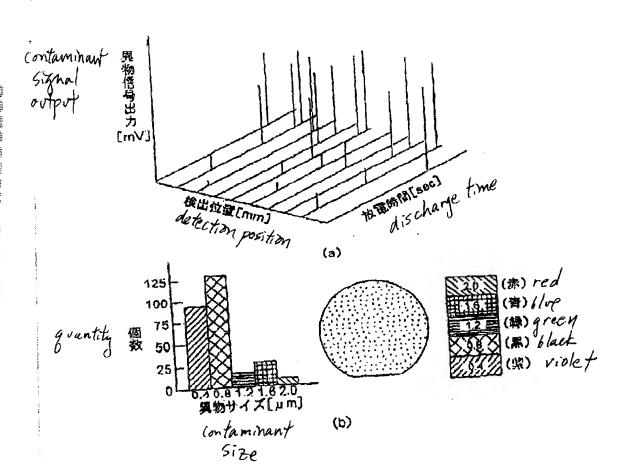
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ファイル名 - D99008581A1.el

[B]8]

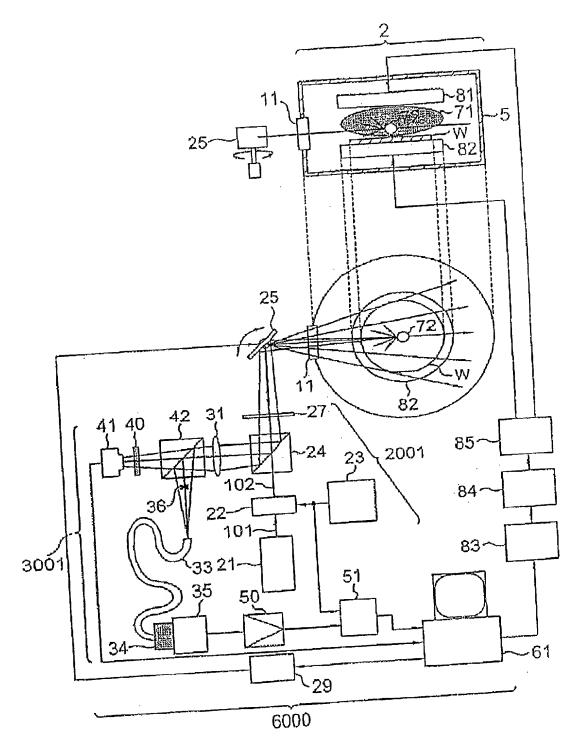
18 Fig 8



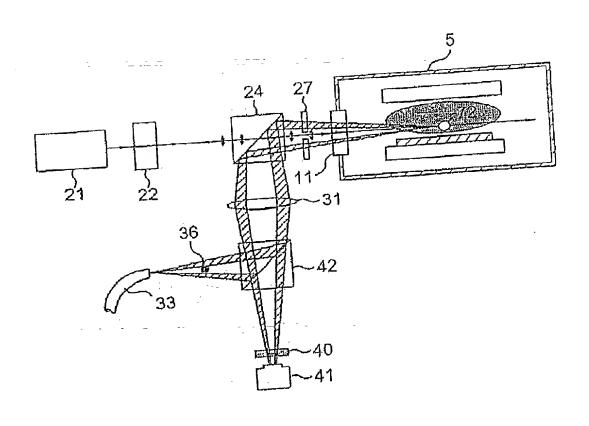
The state of the s

【図9】



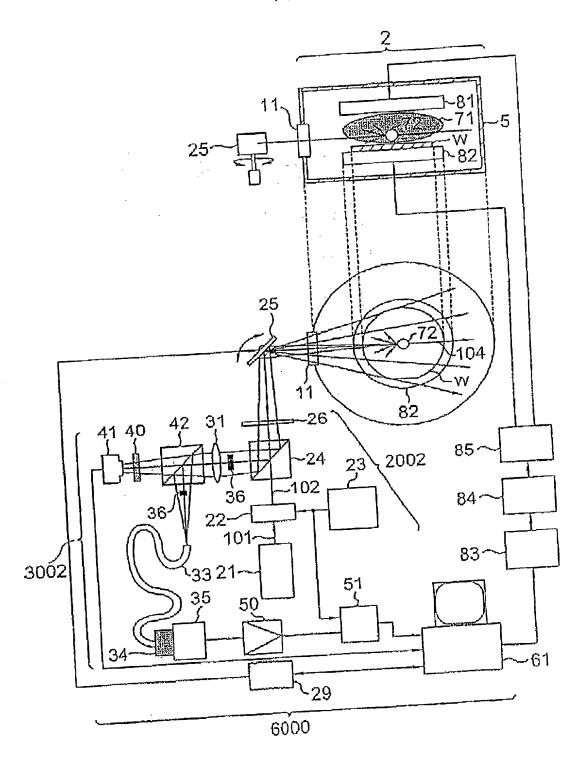


【図10】



[図11]

図11



[図12]

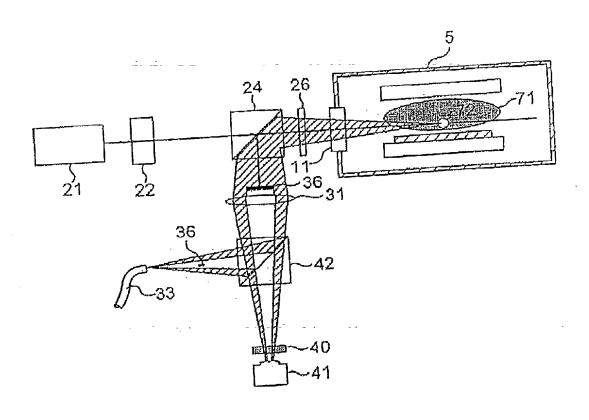
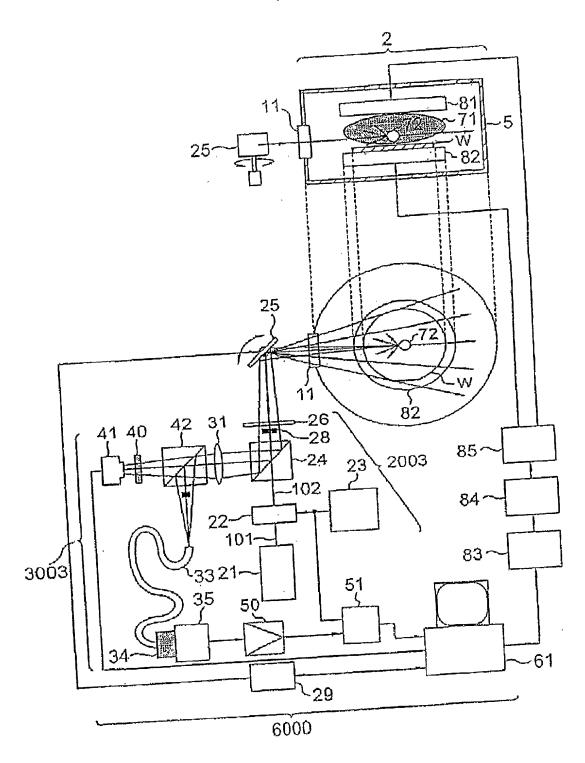
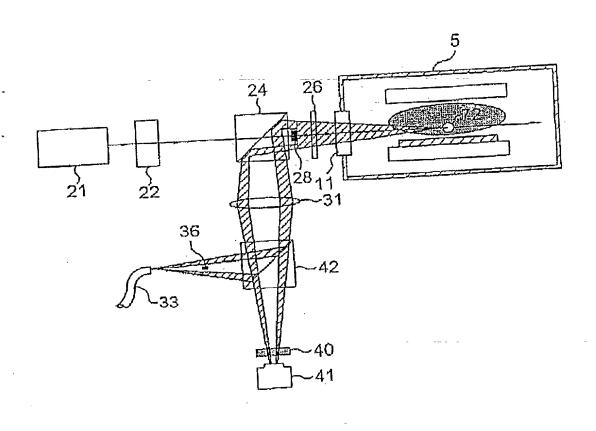


図13



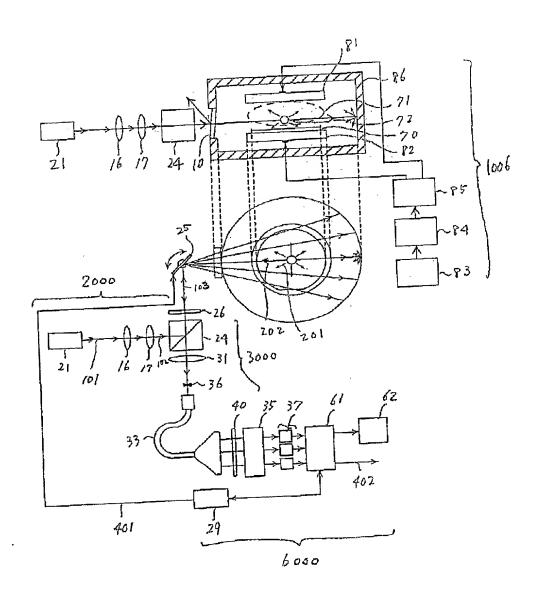
【図14】

図14



[図15]

図15



2000年12月 8日 17年21会

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No. 8764 7. 63

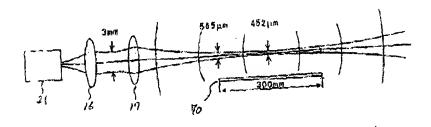
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[31 1 8]

図18



[M19]

19 Fig. 19

The facility of the facility o

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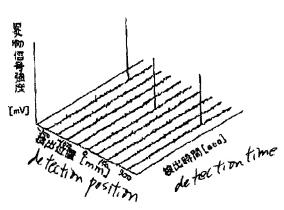
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(図20)

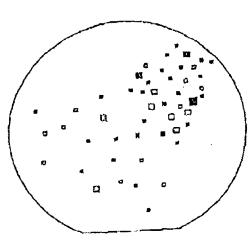
图 2 0

contaminant signal strength

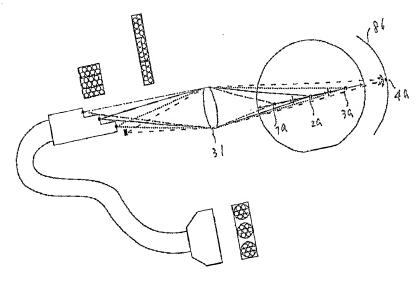


[图21]

图21



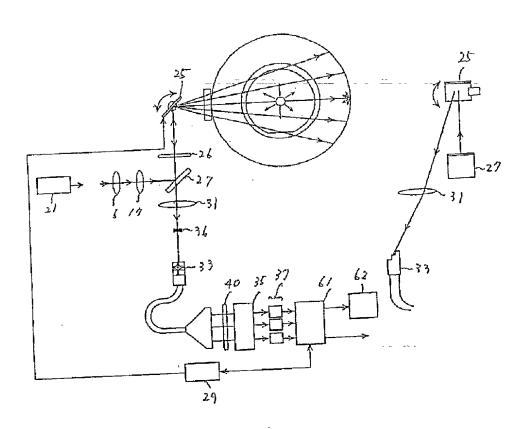
- a 0.2~0.4µm
- . 0.4~0,6pm
- D 0,6~0.8µm
- pp 0. Որտ ≦



(中文型集^{化)}

【図23】

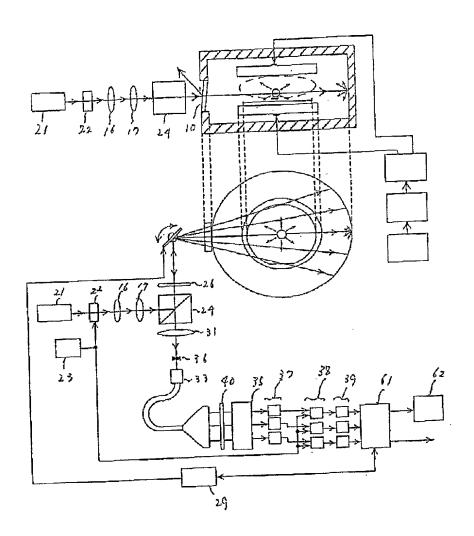
図23



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【図24】

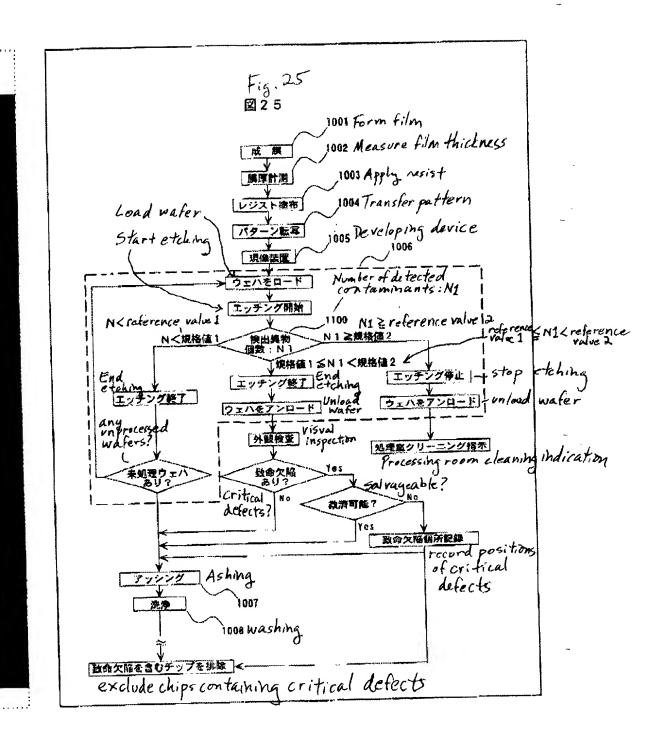
図24

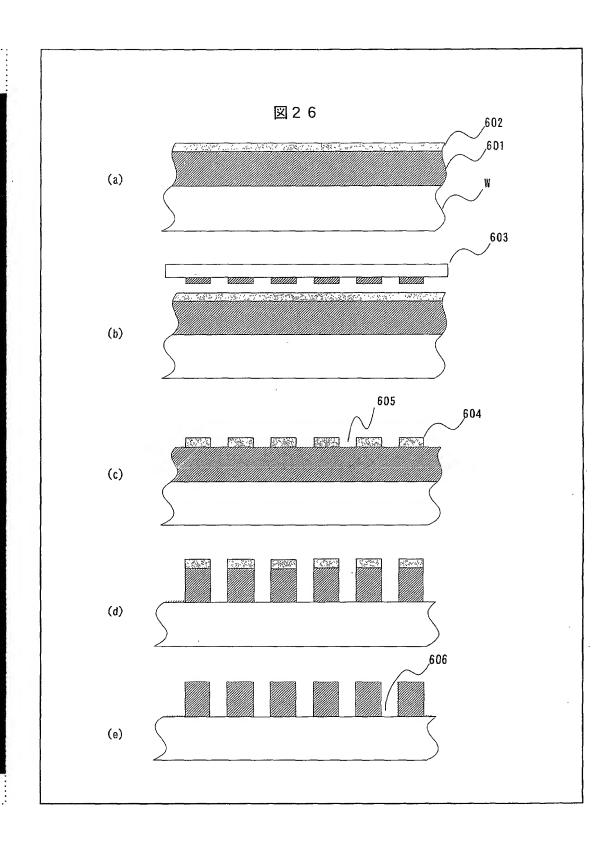


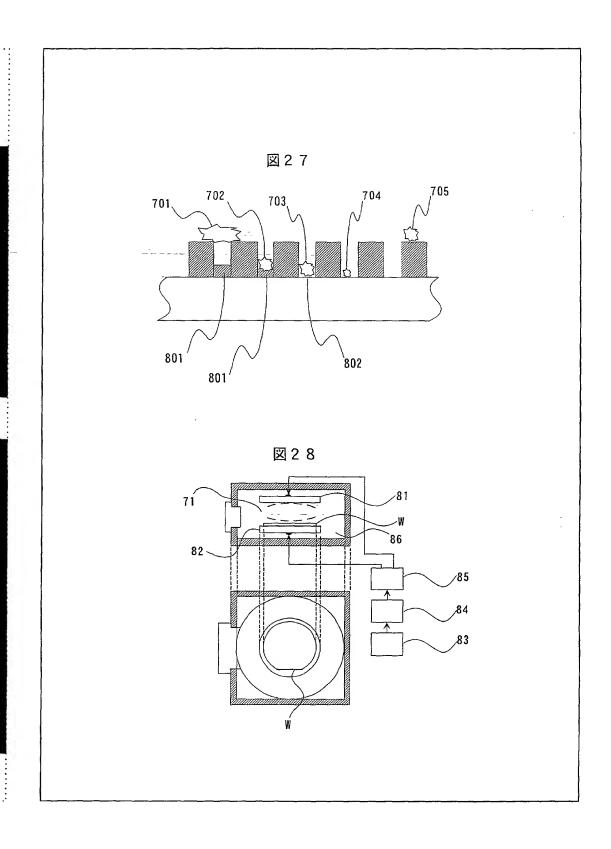
2000年12月 8日 17時22分

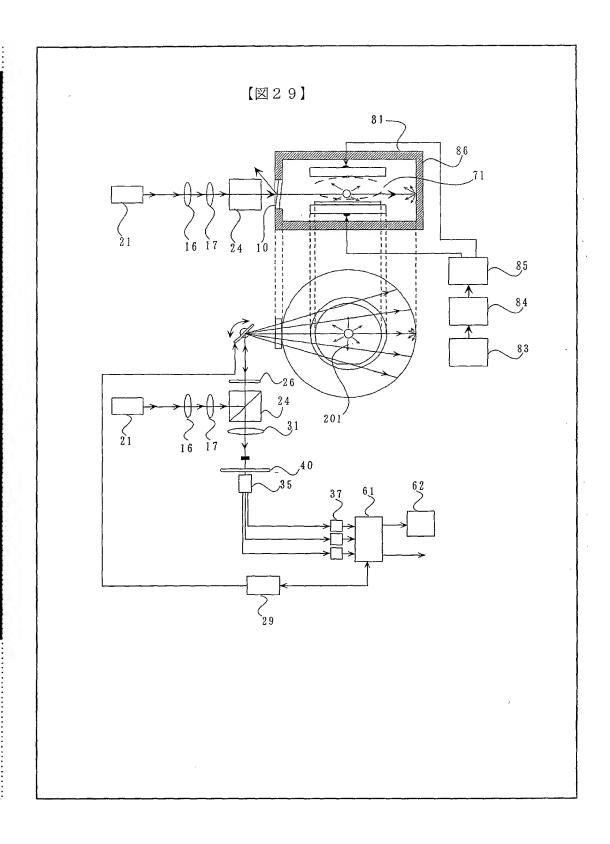
巴立 横浜知本許2

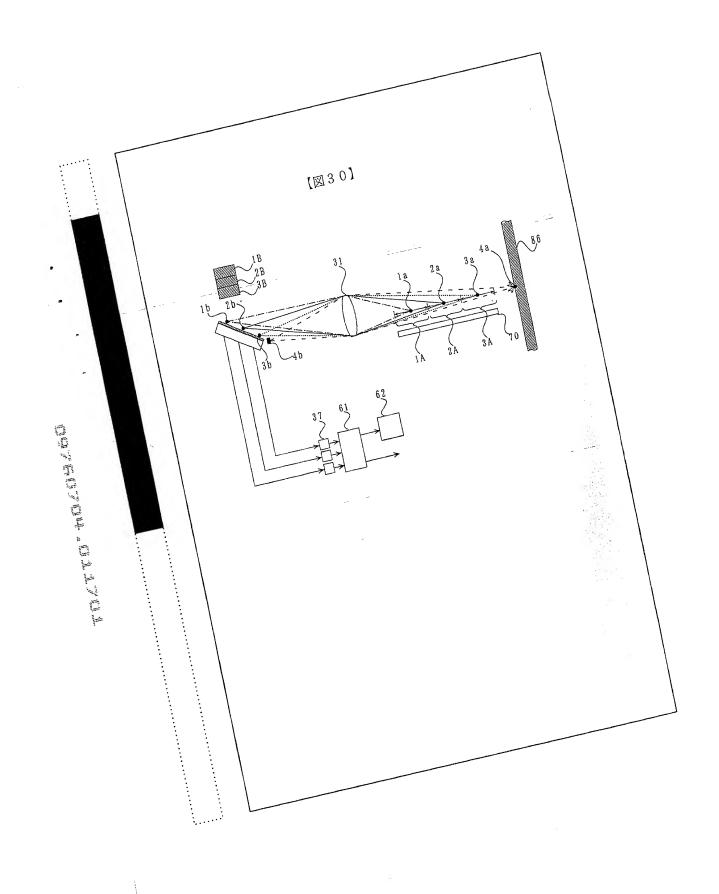
No. 3761 = 63

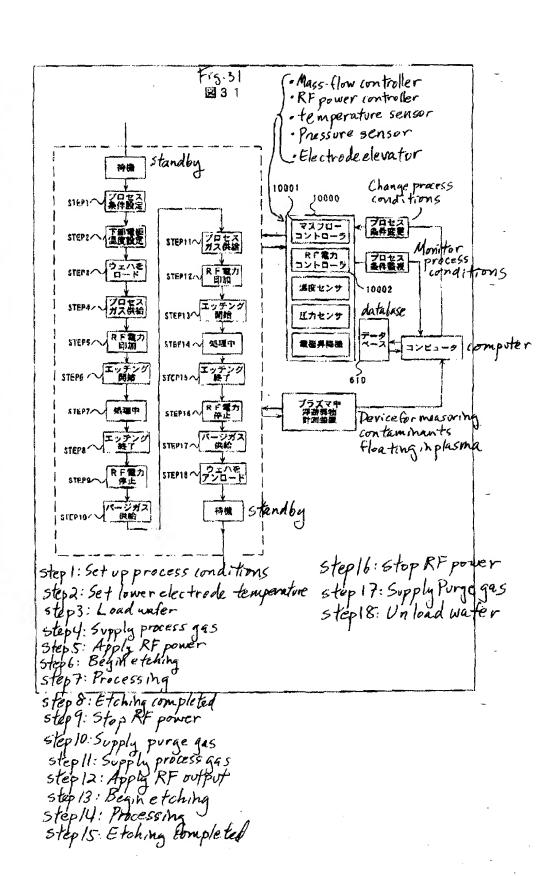




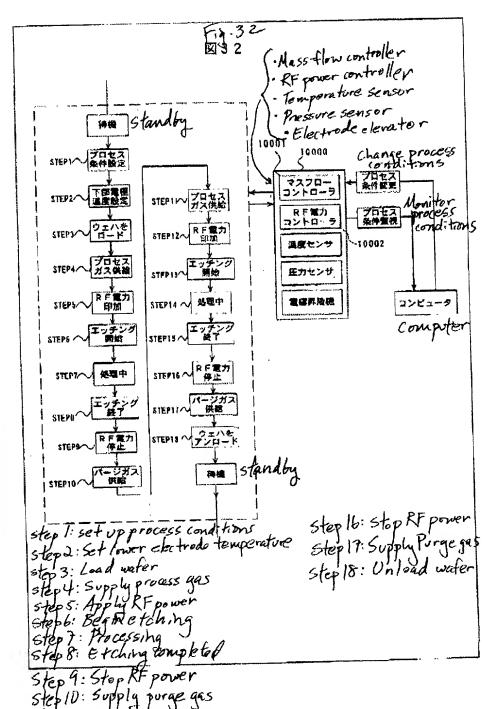








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Step 9: Stop KF power
Step 10: Supply purge gas
step 11: Supply process gas
Step 12: Apply FF output
step 13: Beam etching
Step 14: Prolessing
Step 15: Etching completed